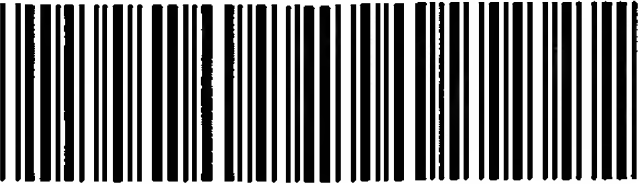


<div>Search Notes</div> <div></div>	Application/Control No.	Applicant(s)/Patent under Reexamination	
	10/618,681	CHEN ET AL.	
	Examiner	Art Unit	
	Stephen M. Hepperle	3753	

SEARCHED			
Class	Subclass	Date	Examiner
127	38 39 315.01	5/05	SMA
73	262		
	263 264		

INTERFERENCE SEARCHED			
Class	Subclass	Date	Examiner
137	38 39 315.01	5/05	SMA
73	262		
	263 264		

SEARCH NOTES (INCLUDING SEARCH STRATEGY)		
	DATE	EXMR
EAST	5/05	SMA